U.S. Department of Commerce, Patent and Trademark Office	
	Application No.: Unknown
	Filing Date: Unknown
	First Named Inventor: Jaime Poris
INFORMATION DISCLOSURE STATEMENT BY APPLICANT	Group Art Unit: Unknown
(Use several sheets if necessary)	Examiner Name: Unknown
	Confirmation No.: Unknown
Copies of References located in Parent Application Serial No. 09/724,813	Attorney Docket No.: NAN042-1D US

U.S. Patent Documents

*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
	1.	5,314,843	5/24/1994	Yu et al	437	225	
	2.	5,348,002	9/20/1994	Caro	128	633	
	3.	5,555,471	10-Sep-96	Xu et al.	356	357	
	4.	5,784,163	7/21/1998	Lu et al	356	351	
	5.	5,872,629	2/16/1999	Colvard	356	349	
	6.	5,874,318	2/23/1999	Baker et al	438	8	
	7.	5,914,782	22-Jun-99	Sugiyama	356	351	
	8.	5,953,115	14-Sep-99	Landers et al.	356	237	
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	12.	6,392,749	21-May-02	Meeks et al.	356	381	
	13.	6,392,752	5/21/2002	Johnson	356	511	

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		Document	Date	Country	Class	Subclass	Translation Yes	No
	14.	EL 0 831 295 A1	3/25/1998	EP				
	15.	EP 0 982 774 A2	3/1/2000	EP				
	16.	WO 00/54325	9/14/2000	PCT				

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	17.	Azzam, R. "Ellipsometery and Polarized Light" Elsevier Science B.V. (1977, 1987), Pages 282-287

Examiner	Date Considered

*EXAMINER: Initial if reference is considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.

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	18.	Fujiwara, H et al., "Dept-profiles in compositionally-graded amorphous silicon alloy thin films analyzed by real time spectroscopic ellipsometry" *Elsevier Science S.A.* pages 474-478 (1998)
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	24.	Makosch, G. et al., "Surface profiling by electro-optical phase measurements" *SPIE* Vol. 316 (1981), pages 42-53
	25.	"Numerical Recipes, The Art of Scientific Computing" by Press, Flannery, Teukolsky and Vetterling, published by Cambridge University Press 1988, 3.2 Rational Function Interpolation and Extrapolation, Pages 83-85... (1988)

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